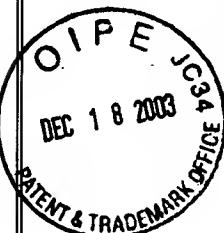


INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)				ATTY. DOCKET NO. 005917 USA/FET/FET	SERIAL NO. 09/998,372	
				APPLICANT Young Joseph PAIK		
				FILING DATE November 30, 2001	GROUP 3723	
U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
<i>BB</i>	4,207,520	06/10/80	Flora et al.			04/06/78
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	4,609,870	09/02/86	Lale et al.			09/13/84
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	5,427,878	06/27/95	Corliss	DEC 23 2003		05/16/94
	5,534,289	07/09/96	Bilder et al.			01/03/95
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	6,442,496	08/27/02	Pasadyn et al.			08/08/00
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<i>BB</i>	6,587,744	07/01/03	Stoddard et al.			06/20/00
FOREIGN PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation
						Yes <input type="checkbox"/> No <input type="checkbox"/>
<i>BB</i>	WO 01/11679	02/15/01	WIPO			X
<i>BB</i>	WO 01/080306	10/25/01	WIPO			X
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)						
<i>BB</i>	Miller, G. L., D. A. H. Robinson, and J. D. Wiley. July 1976. "Contactless measurement of semiconductor conductivity by radio frequency-free-carrier power absorption." <i>Rev. Sci. Instrum.</i> , Volume 47, No. 7. pp. 799 – 805.					
<i>BB</i>	1999. "Contactless Bulk Resistivity/Sheet Resistance Measurement and Mapping Systems." www.Lehighton.com/fabtech1/index.html .					
<i>BB</i>	2000. "Microsense II Capacitance Gaging System." www.adetech.com .					
EXAMINER	<i>BB</i>			DATE CONSIDERED <i>3/29/04</i>		

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)		ATTY. DOCKET NO. 005917 USA/FET/FET		SERIAL NO. 09/998,372			
 RECEIVED DEC 23 2003 TECHNOLOGY CENTER R3700		APPLICANT Young Joseph PAIK					
		FILING DATE November 30, 2001		GROUP 3723			
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						<input type="checkbox"/> Yes	<input type="checkbox"/> No
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<p><i>BB</i></p> <p>El Chemali, Chadi et al. July/August 2000. "Multizone uniformity control of a chemical mechanical polishing process utilizing a pre- and postmeasurement strategy." <i>J. Vac. Sci. Technol.</i> Volume 18, No. 4. pp. 1287 – 1296.</p> <p>March 5, 2001. "KLA-Tencor Introduces First Production-worthy Copper CMP In-situ Film Thickness and End-point Control System." http://www.kla-tencor.com/j/servlet/NewsItem?newsItemID=74.</p> <p>2002. "Microsense II – 5810: Non-Contact Capacitance Gaging Module." www.adetech.com.</p> <p>08 August 2003. PCT International Search Report from PCT/US03/08513.</p> <p>14 October 2003. PCT International Search Report from PCT/US02/21942.</p> <p>20 October 2003. PCT International Search Report from PCT/US02/19116.</p> <p>23 October 2003. PCT International Preliminary Examination Report from PCT/US01/24910.</p> <p>"NanoMapper wafer nanotopography measurement by ADE Phase Shift." http://www.phase-shift.com/nanomap.shtml.</p> <p>"Wafer flatness measurement of advanced wafers." http://www.phase-shift.com/wafer-flatness.shtml.</p> <p>"ADE Technologies, Inc. – 6360." http://www.adetech.com/6360.shtml.</p> <p><i>VV</i></p> <p>"3D optical profilometer MicroXAM by ADE Phase Shift." http://www.phase-shift.com/microxam.shtml.</p> <p><i>BB</i></p> <p>"NanoMapper FA factory automation wafer nanotopography measurement." http://www.phase-shift.com/nanomapperfa.shtml.</p>							
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FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
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BS	Rocha, Joao and Carlos Ramos. September 12, 1994. "Task Planning for Flexible and Agile Manufacturing Systems." <i>Intelligent Robots and Systems '94. Advanced Robotic Systems and the Real World, IROS '94. Proceedings of the IEEE/RSJ/GI International Conference on Munich, Germany 12-16 Sept. 1994.</i> New York, New York: IEEE. pp. 105-112.
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